

METHOD FOR MANUFACTURING A THIN FILM MAGNETIC HEAD

ABSTRACT

After applying a metal film (2) on a surface of a substrate (1), the metal film (2) is patterned in such a manner that the surface of the substrate (1) is exposed in a pattern that corresponds to the pattern of the required indented portion (6). Then, the substrate (1) is immersed in an etchant which etches the substrate (1) selectively to form the indented portion (6) in the surface of the substrate (1) using the metal film (2) as a mask.

The method makes it possible to define the depth (d) and the pattern of an indented portion (6) where a magnetic transducer (9) is provided with a high degree of accuracy, to prevent a reduction in pattern accuracy due to re-adhering and to advance industrial productivity.

Figure 10.